Biography:

CRAIG L. KEAST is the leader of the Advanced Silicon Technology group and Director of Operations for the Microelectronics Laboratory at MIT Lincoln Laboratory. The Advanced Silicon Technology group's current research activities center on deep-submicron, low-power, high-performance fully depleted silicon-on-insulator (FDSOI) CMOS process development, CCD/CMOS imaging, RF MEMS, and 3-dimensional circuit integration technologies. Dr. Keast received a B.A. degree from Hamilton College and S.M., E.E., and Ph.D. degrees in electrical engineering and computer science from the Massachusetts Institute of Technology.